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Application Number	Not yet assigned
Filing Date	Herewith
First Named Inventor	James S. Im
Art Unit	Not yet assigned 2823
Examiner Name	Not yet assigned W. David Coleman
Attorney Docket Number	A35185-PCT-USA (070050.2727)

Sheet	1	of	1
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Form PTO-1449 U.S. Department of Commerce (REV. 2-82) Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Atty. Docket No. A35185-PCT-USA (070050.2727)	Serial No. 10/525,283
	Applicant James S. Im	
	Filing Date 02/16/2005	Group TBD 2823
	Examiner Not yet assigned	W. David Coleman

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Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
W.C.	130	6582827	06/24/2003	Im
W.C.	33	6830993	12/14/2004	Im et al.



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Exam Initial	No.	Document No.	Publication Date	Country	Translation	
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Exam Initial	No.	Document No.	Publication Date	Country	Translation	
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant James S. Im	
	Filing Date 02/16/2005	Group TBD 2823
	Examiner Not yet assigned	W. David Coleman

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